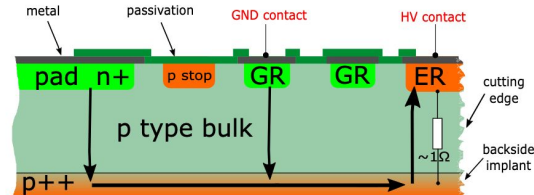
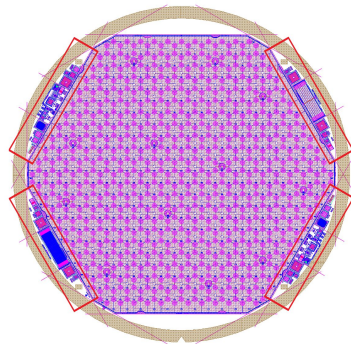


Studies of surface radiation damage with CMS HGCAL test diodes

Eva Fialová, Matteo Defranchis
4th DRD3 week on Solid State Detectors R&D
12.11.2025

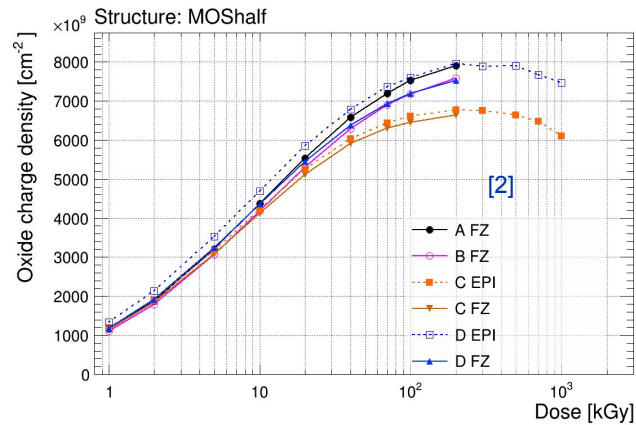
E. Fialova et al, "Novel method to assess the electromagnetic radiation damage using HGAL silicon sensors",
[10.1088/1748-0221/20/07/C07061](https://doi.org/10.1088/1748-0221/20/07/C07061)

CMS HGICAL - Si sensors



Figures by Peter Paulitsch

- **High Granularity Calorimeter (HGICAL):** forward sampling calorimeter for HL phase 2 of the LHC [1]
- HGICAL will feature 8" hexagonal *n-on-p* type Si sensors (Hamamatsu)
- Test structures printed on the **cutted edges** from the circular wafer, used to perform destructive tests
- **X-ray irradiation:** studies of EM radiation damage in **SiO₂**
- Preproduction phase multiple oxide variants
- Based on the MOS measurements oxide **Type C** was selected for production [2]

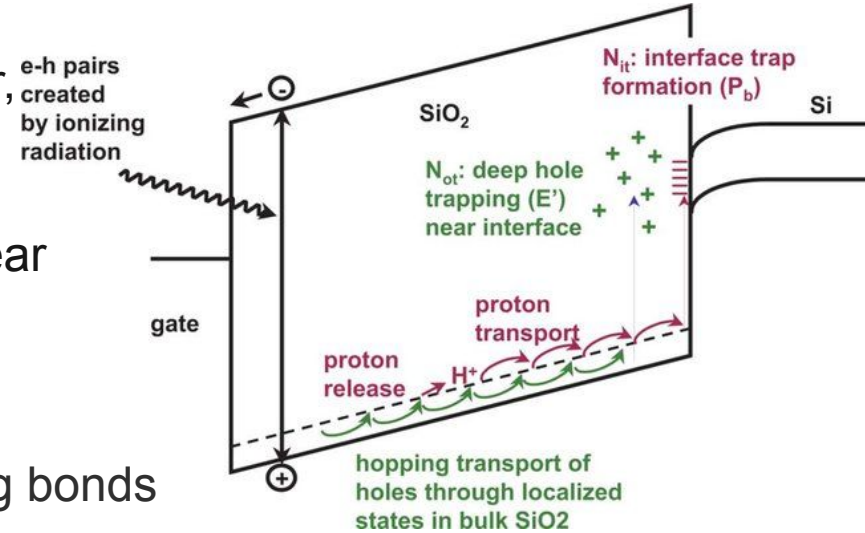


[1]CMS collaboration, [The Phase-2 Upgrade of the CMS Endcap Calorimeter](#).

[2]Matteo Defranichis, "[Characterisation of the silicon oxide quality in CMS HGICAL sensor prototypes](#)", presentation at the TRENTO workshop

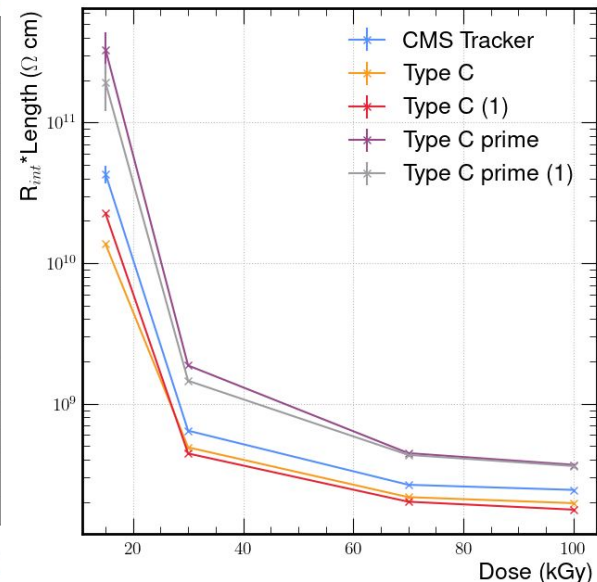
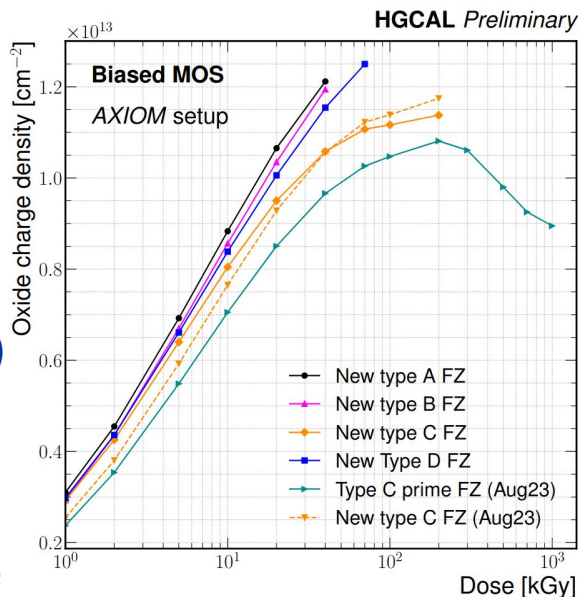
Surface damage from electromagnetic radiation

- EM radiation \rightarrow e/h pairs in the SiO_2 layer, fraction recombines
- Electrons collected at the electrodes
- Holes slowly diffuse \rightarrow can be trapped near the Si/SiO_2 interface
- **Oxygen vacancies**: trapping centers for holes \rightarrow **positive oxide charge N_{ox}**
- **Interface traps N_{it} (P_b centers)**: dangling bonds formed at the Si/SiO_2 interface
- Number of N_{ox} and N_{it} depends on dose, electric field, annealing time and temperature, crystal orientation, and oxide quality



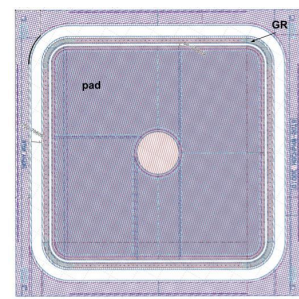
Motivation: interstrip resistance and MOS measurements

- **Type C prime** oxide: possibly higher quality than Type C
- Measurements of **interstrip resistance (R_{int})** with strip test structures [4]
- Results show no clear preference between different oxide variants due to the difference in p -stop concentration
- Need for a new method

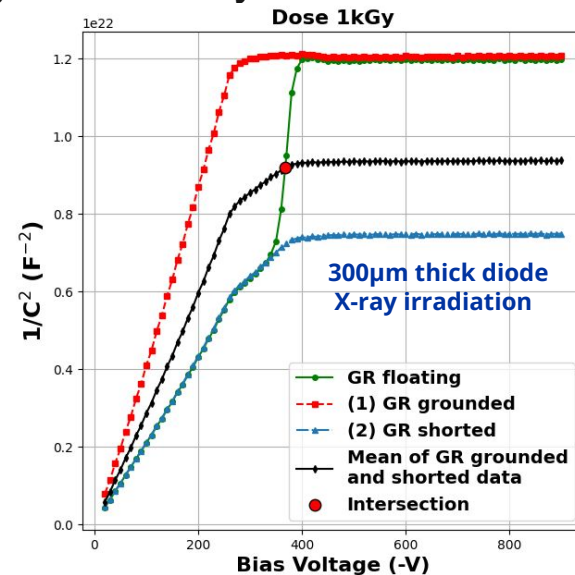


[4]Pablo Alvarez Domínguez, "[Comparison of X-ray radiation damage for different oxide types in HGCAL silicon sensors prototypes](#)", presentation at the DRD3 Workshop

Interpad isolation - $V_{th,iso}$



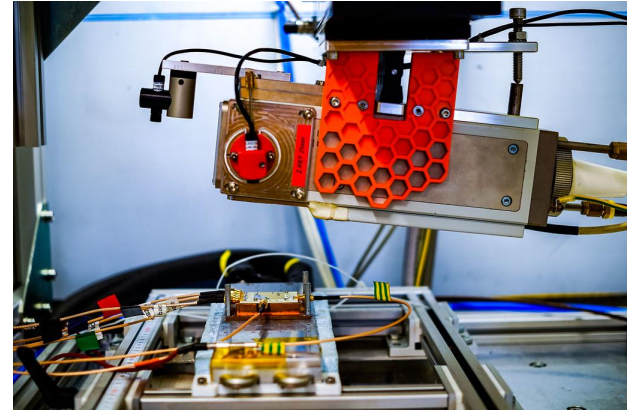
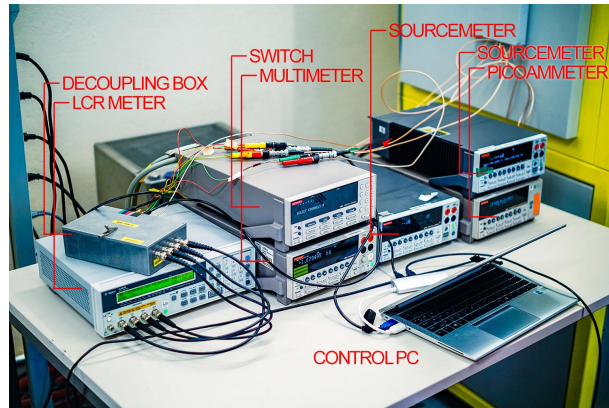
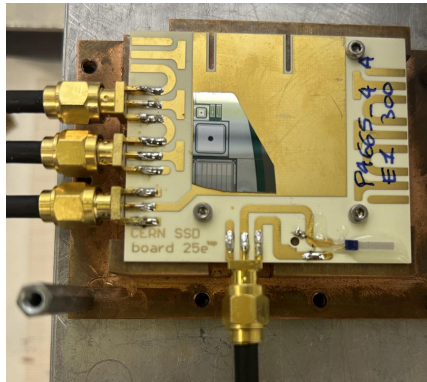
- **Threshold voltage of inter-electrode isolation ($V_{th,iso}$):** voltage when the $n+$ -electrodes become electrically isolated by the influence of applied reverse biased voltage [5]
- Investigation of regions without isolation implants between $n+$ -electrodes :
diode pad + guard ring
- **Better oxide quality -> lower $V_{th,iso}$**



[5] Timo Peltola, "A method to observe field-region oxide charge and inter-electrode isolation from CV-characteristics of n -on- p devices"

X-ray irradiation at CERN

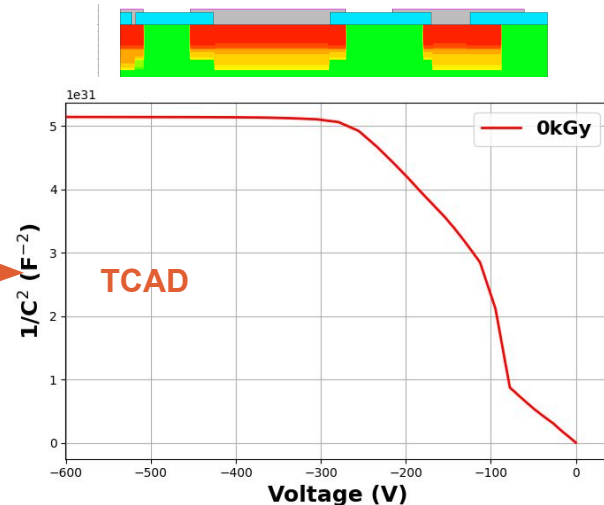
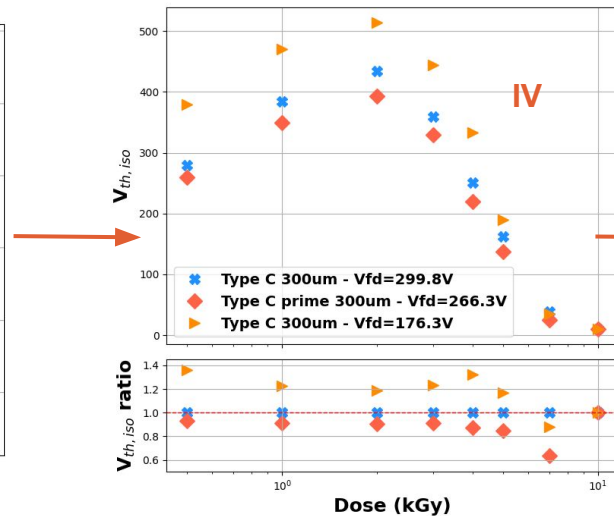
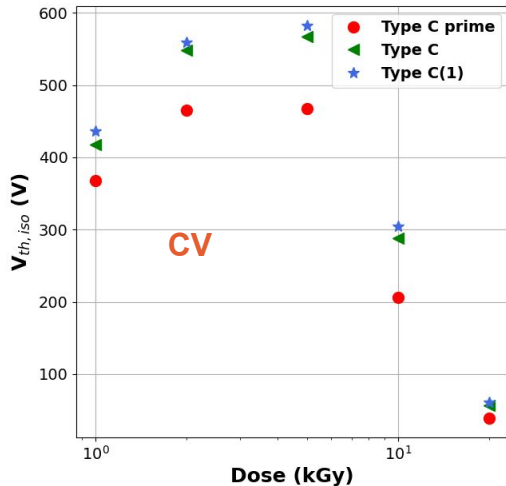
- ObeliX X-ray irradiation system (EP-ESE-ME group)[6]
- Irradiation and measurements at -20°C -> **to avoid annealing**
- Fully automated measurement setup
- Fixed dose rate for all dose steps:
24.6kGy/h for CV and R_{int} , and 13.1kGy/h for IV measurements



[6] <https://ep-ese-me-xray.web.cern.ch/ObeliX/>

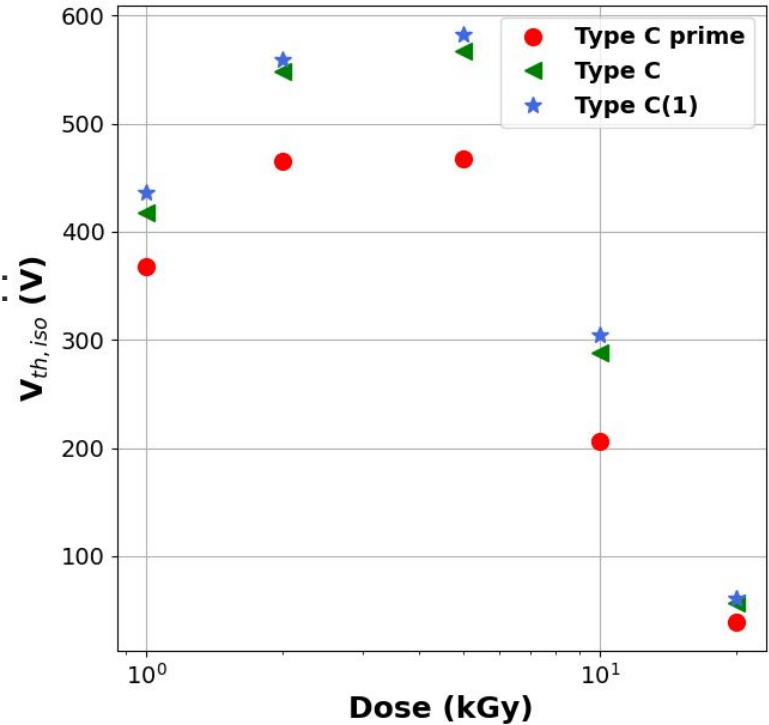
$V_{th,iso}$ measurements: how the story went

- **Initial approach: CV measurements** (GR floating, grounded, and shorted)
- Further investigations -> $V_{th,iso}$ extraction from **IV measurements**
- For full understanding -> **TCAD simulations**



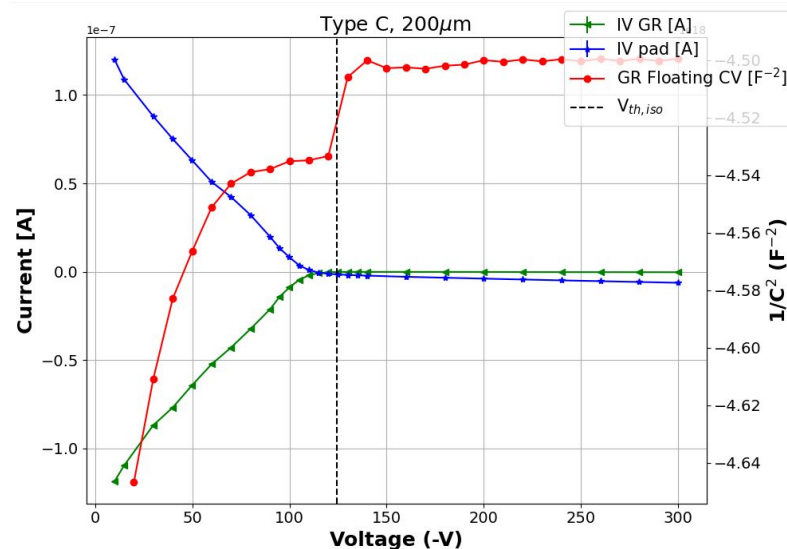
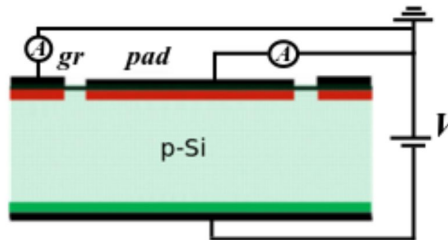
$V_{th,iso}$: CV measurements

- **Motivation:** method to compare **Type C** and **C prime** oxide
- **C prime lower $V_{th,iso}$**
- Unexpected dependence of $V_{th,iso}$ on dose: **decrease in $V_{th,iso}$** after a peak at 5kGy
- Possible issue: capture and emission rate of $N_{it,acc/don}$ dependent on frequency \rightarrow **interpad resistance R_{int}** measurements
- Reproducibility below $\leq 3\%$



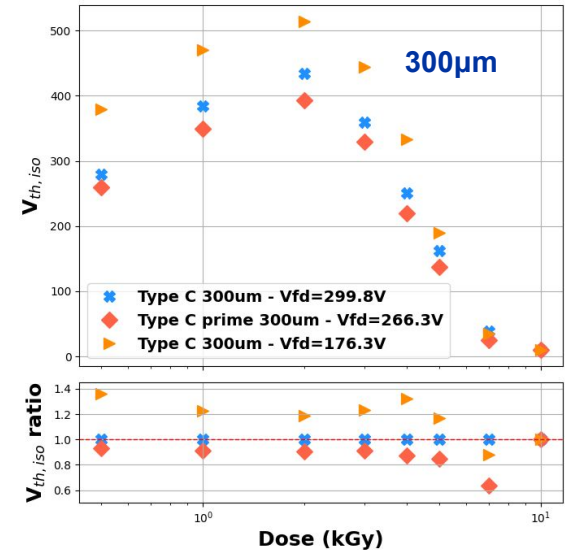
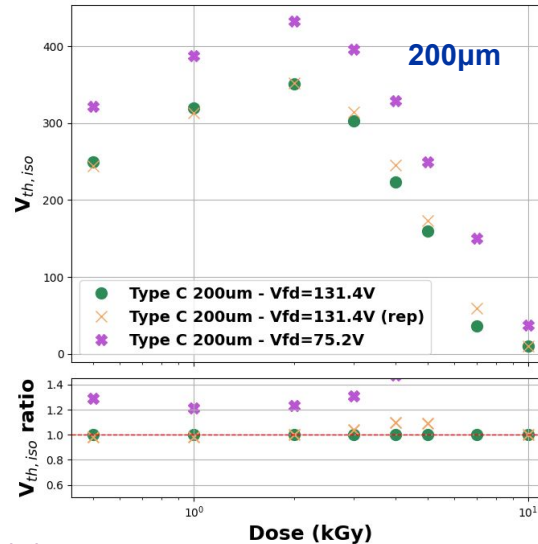
$V_{th,iso}$ - IV measurements

- Robust method to confirm previous results: biasing the backplane and measuring the currents separately from the pad and guard ring
- Point where two curves meet corresponds to $V_{th,iso}$



$V_{th,iso}$ - IV measurements

- Type C prime oxide - **lower $V_{th,iso}$** , same as CV results (300um samples)
- New observation: bulk properties before irradiation (V_{fd}) influence the surface properties after irradiation
- Deliberate selection of samples with extreme V_{fd} values [7]
- Results reproducible within less than 10% (200um samples)



[7]Timo Peltola, [Understanding CV-results of test diodes & MOSCAPs of HGCAL production sensors by TCAD simulations](#)

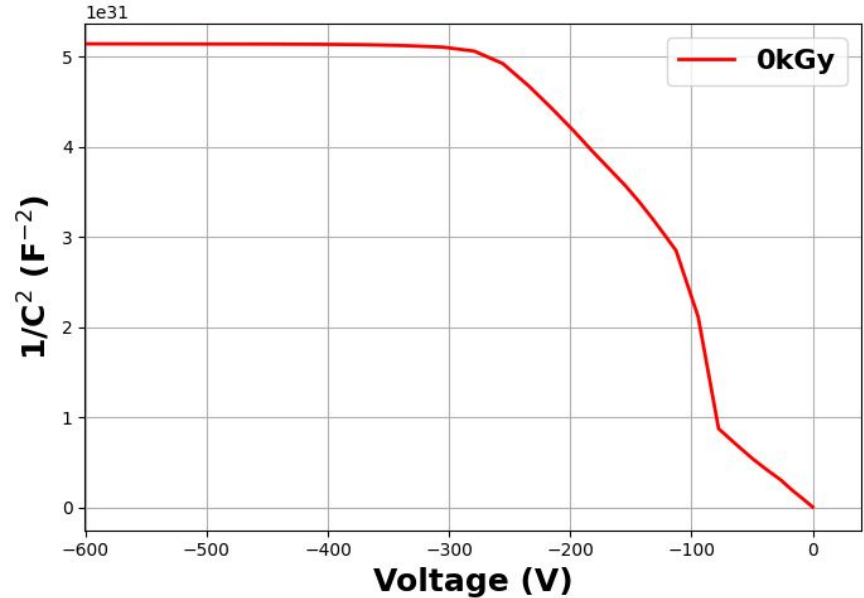
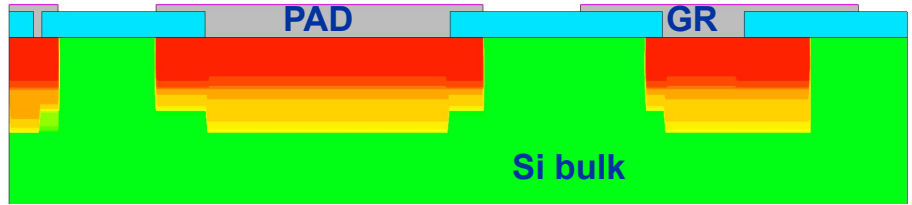
Remaining question

- **Why does $V_{th,iso}$ decrease after a certain dose?**
 - Possible explanation: **difference in the introduction rate of donor-like and acceptor-like interface traps ($N_{it,acc}$ vs $N_{it,don}$)**[6]
- Investigation using Synopsys TCAD simulations

[6]G. Borghello, "Ionizing radiation effects in nanoscale CMOS technologies exposed to ultra-high doses"

TCAD simulations

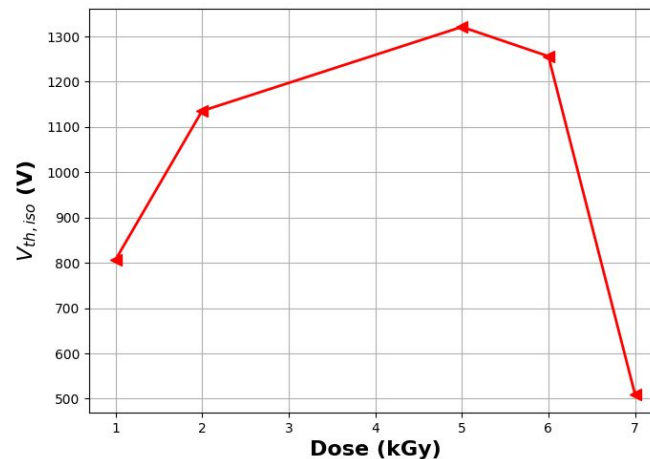
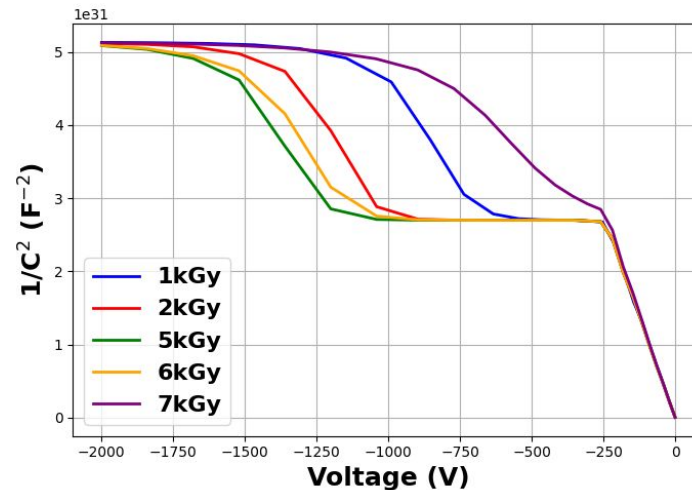
- 2D diode simulation of the CV measurements
- Surface radiation damage simulation: **Perugia model [7]**
- Model differentiates between N_{ox} , $D_{it,acc}$ and $D_{it,don}$ to describe surface radiation damage



[7] Arianna Morozzi, "TCAD Modeling of Surface Radiation Damage Effects: A State-Of-The-Art Review"

TCAD simulations

- Simulations predict higher $V_{th,iso}$ values than measurements -> model not tuned for these structures
- **Decrease in $V_{th,iso}$**
- **Parameters set to arbitrary values:** model needs parameter tuning (MOS, GCD) -> comparison with measurements
- Improvement compare to the previous simulations, where $V_{th,iso}$ only increased with dose
- $D_{it,acc}$ has a major impact on the $V_{th,iso}$



Conclusions

- Type **C prime** shows **lower $V_{th,iso}$** -> preferable oxide for future uses
- $V_{th,iso}$ peaks between 2-5 kGy, followed by sharp decrease at higher doses, likely due to the **difference in introduction rate of $N_{it,don}$ vs $N_{it,acc}$**
- Correlation between the bulk properties before irradiation and surface properties after irradiation
- **CV-based extraction** shows the **best reproducibility** -> recommended method for $V_{th,iso}$ estimation
- TCAD simulations confirm the influence of introduction rate of acceptor and donor-like interface traps on $V_{th,iso}$

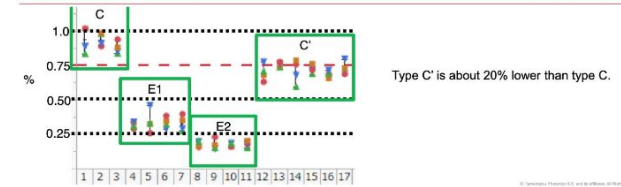
Backup

Oxide variants

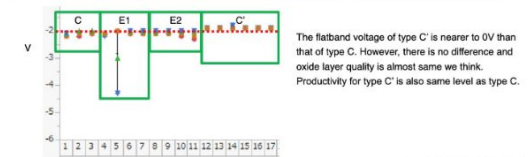
| | Vfb | p-stop | oxide quality improvement | p-stop concentration | comment |
|----|-----|--------|---------------------------|----------------------|---|
| A | -5V | common | STD | STD | not improved Vfb & STD condition (for ref.) |
| B | -2V | common | STD | STD | improved Vfb with special masking method |
| C | -2V | common | thermal condition change | STD | (for ref.) production condition |
| C' | -2V | common | thermal condition change | STD | more close to 6" line than type C |
| D | -2V | common | combination of B and C | STD | CMS required condition |
| E1 | -2V | common | thermal condition change | x2.5 | combination C and p-stop concentration |
| E2 | -2V | common | thermal condition change | x5.0 | |

- 300 μ m float zone, $V_{dep} \approx 270V$
- MOSFET measurements indicate **higher p-stop concentration** for Type C prime than for Type C

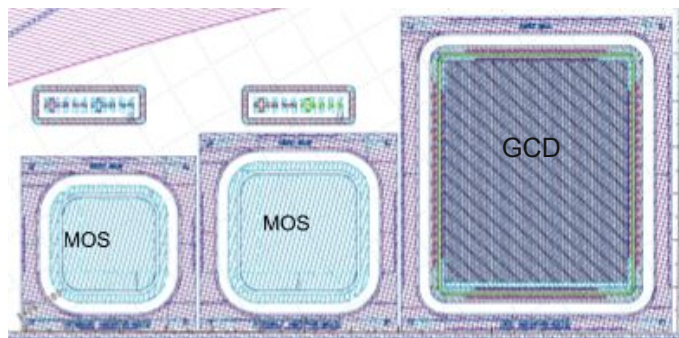
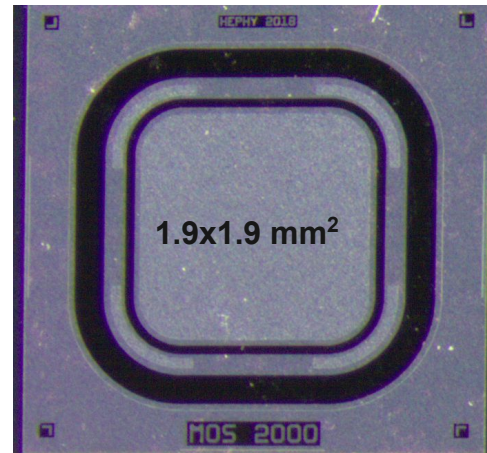
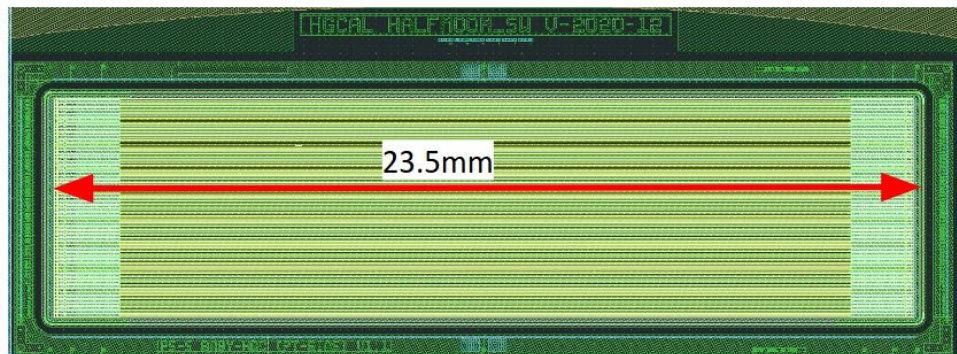
P-stop resistance for each condition



Flatband voltage for each condition

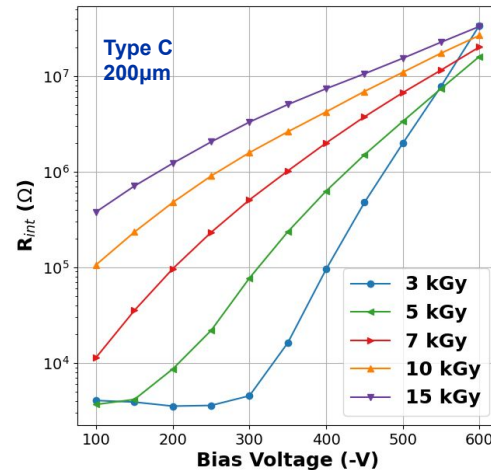
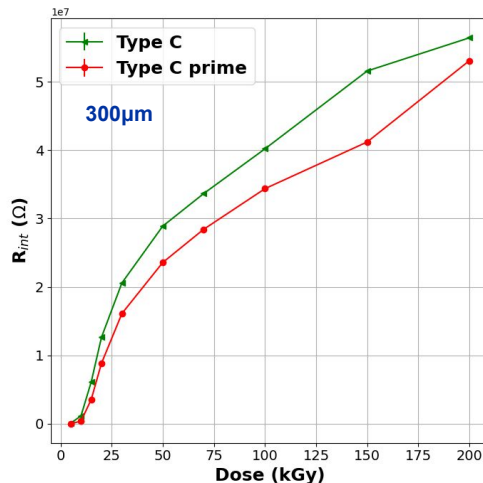
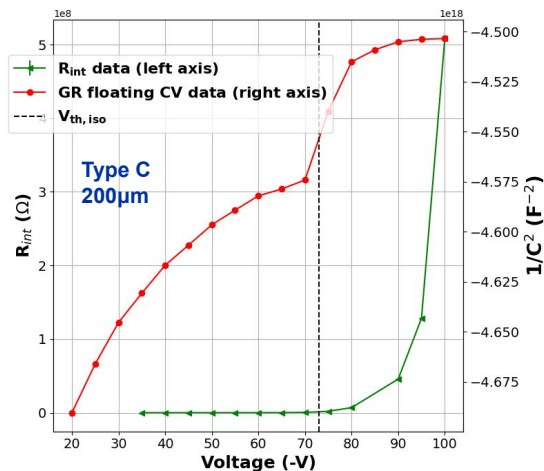


Test structures



R_{int} measurements

- Interstrip-like measurements with **diode pad** and **GR** (no p -stop, but different geometry)
- R_{int} **increases with dose**, contrary to previous measurements with strips
- Increase in R_{int} corresponds to the $V_{th,iso}$
- Possible correlation between **increase in R_{int}** and **decrease in $V_{th,iso}$** with increasing dose



$V_{th,iso}$ estimation from the IV measurements

- $V_{th,iso}$ estimated using the RMS of the difference of the GR and pad current
- The RMS is computed over a sliding window of 5 voltage points
- $V_{th,iso}$ is computed as:
$$\Delta I(V_{th,iso}) = \Delta I_{min} + 0.01 * (\Delta I_{max} - \Delta I_{min})$$

